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1. Name of conveying party(ies):
Mosel Vitelic, Inc.

Additional name(s) of conveying party(ies) attached? ☐ Yes ☑ No

3. Nature of conveyance:
☑ Assignment ☐ Merger
☐ Security Agreement ☐ Change of Name
☐ Other_____

Execution Date: April 27, 2004

2. Name and address of receiving party(ies)
Name: ProMOS Technologies Inc.
Internal Address: _____
Street Address: 3F, No. 19, Li-Hsin Road
Science-Based Industrial Park
City: Hsin-Chu City State:____ Zip: TAIWAN

Additional name(s) & address(es) attached? ☐ Yes ☑ No

4. Application number(s) or patent number(s):
If this document is being filed together with a new application, the execution date of the application is: N/A
A. Patent Application No.(s) _____
B. Patent No.(s) 4,868,617; 4,888,734; 4,888,735 (see attachment)

Additional numbers attached? ☑ Yes ☐ No

5. Name and address of party to whom correspondence concerning document should be mailed:
Name: Michael Shenker
Internal Address: _____
Street Address: MacPherson Kwok Chen & Heid LLP
1762 Technology Drive, Suite 226
City: San Jose State: CA Zip: 95110

6. Total number of applications and patents involved: 371

7. Total fee (37 CFR 3.41).....$ 14,840
☐ Enclosed
☑ Authorized to be charged to deposit account

8. Deposit account number:
50-2257

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Michael Shenker, Reg. No. 34,250 — Name of Person Signing
Michael Shenker — Signature
5-19-04 — Date

Total number of pages including cover sheet, attachments, and documents: 18

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Washington, D.C. 20231

05/25/2004 LMUELLER 00000130 502257 4868617
01 FC:8021 14840.00 DA

Attachment Sheet
Patent Nos. for Recordation

5,148,056	5,788,567	5,942,041
5,192,916	5,789,267	5,946,568
5,327,026	5,789,296	5,947,802
5,345,195	5,789,297	5,957,764
5,347,171	5,792,686	5,960,279
5,347,172	5,804,091	5,963,806
5,373,470	5,804,493	5,963,830
5,412,257	5,811,344	5,964,413
5,430,680	5,811,358	5,965,462
5,438,287	5,811,864	5,966,626
5,440,246	5,818,291	5,966,632
5,461,590	5,821,564	5,970,360
5,481,581	5,824,234	5,972,746
5,514,609	5,824,578	5,972,754
5,516,711	5,827,747	5,973,980
5,547,882	5,827,780	5,977,608
5,606,191	5,827,783	5,980,368
5,643,632	5,837,578	5,986,474
5,644,545	5,841,718	5,989,971
5,646,074	5,843,822	6,000,997
5,650,341	5,851,867	6,001,697
5,663,915	5,851,898	6,001,745
5,671,392	5,851,900	6,008,106
5,672,243	5,852,573	6,008,515
5,679,595	5,858,867	6,008,688
5,681,772	5,869,394	6,010,938
5,686,324	5,869,399	6,010,944
5,691,223	5,869,406	6,017,816
5,691,240	5,877,073	6,019,664
5,691,562	5,877,638	6,020,231
5,696,016	5,879,988	6,020,259
5,696,036	5,880,496	6,025,245
5,698,903	5,882,984	6,025,981
5,701,013	5,883,015	6,027,761
5,703,388	5,885,866	6,030,893
5,724,825	5,892,232	6,031,407
5,726,086	5,908,659	6,037,208
5,728,598	5,909,621	6,037,251
5,733,114	5,917,214	6,037,624
5,747,357	5,920,780	6,040,216
5,747,368	5,926,712	6,042,457
5,747,378	5,926,715	6,043,547
5,760,484	5,930,593	6,044,018
5,770,515	5,930,631	6,046,092
5,776,833	5,934,974	6,054,350
5,783,473	5,937,907	6,057,197

6,057,576	6,136,653	6,236,327
6,059,643	6,144,059	6,240,034
6,062,959	6,146,249	6,241,597
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6,069,052	6,149,078	6,242,774
6,069,088	6,149,512	6,244,945
6,071,794	6,150,238	6,245,148
6,074,291	6,150,244	6,245,467
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6,080,595	6,159,083	6,249,469
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6,083,792	6,162,724	6,255,188
6,084,803	6,163,492	6,255,205
6,086,456	6,165,843	6,261,893
6,088,270	6,171,904	6,261,903
6,090,680	6,171,927	6,261,926
6,090,725	6,172,554	6,261,930
6,093,627	6,180,980	6,261,966
6,096,645	6,184,092	6,265,233
6,098,901	6,184,093	6,265,269
6,099,386	6,185,159	6,265,754
6,100,126	6,188,072	6,266,266
6,100,561	6,190,928	6,266,290
6,107,193	6,190,990	6,267,655
6,110,801	6,191,003	6,271,079
6,110,810	6,191,986	6,271,556
6,113,736	6,191,997	6,273,953
6,114,209	6,194,269	6,273,962
6,117,727	6,194,272	6,274,509
6,117,755	6,195,302	6,275,432
6,117,780	6,197,659	6,284,578
6,121,107	6,201,413	6,291,827
6,121,116	6,204,547	6,297,088
6,124,178	6,204,677	6,299,218
6,126,512	6,208,574	6,299,788
6,126,527	6,218,267	6,303,436
6,127,075	6,218,275	6,310,688
6,127,699	6,222,776	6,315,857
6,128,070	6,228,661	6,319,795
6,128,236	6,228,729	6,322,429
6,130,433	6,228,776	6,324,097
6,133,155	6,232,199	6,326,320
6,133,597	6,235,592	6,326,574
6,136,647	6,235,604	6,331,721

Attachment Sheet
Patent Nos. for Recordation

6,332,275	6,445,621
6,334,258	6,454,641
6,335,260	6,465,369
6,336,787	6,469,341
6,337,278	6,469,559
6,337,830	6,491,178
6,339,354	6,492,188
6,342,426	6,492,248
6,346,418	6,492,263
6,346,474	6,500,712
6,346,839	6,503,824
6,352,908	6,506,615
6,355,524	6,509,198
6,355,974	6,515,327
6,358,676	6,531,387
6,358,864	6,538,455
6,359,487	6,543,980
6,365,064	6,544,847
6,365,455	6,551,900
6,365,524	6,559,055
6,368,882	6,562,681
6,373,778	6,563,166
6,374,833	6,563,747
6,375,194	6,566,196
6,376,300	6,568,988
6,380,072	6,570,215
6,384,482	6,571,488
6,386,139	6,584,018
6,386,213	6,584,578
6,388,265	6,597,201
6,391,739	6,606,088
6,392,304	6,613,672
6,397,480	6,617,636
6,399,437	6,621,747
6,399,980	6,632,685
6,403,489	6,643,186
6,406,209	6,645,808
6,406,953	6,647,607
6,414,350	6,654,291
6,415,374	6,657,263
6,417,099	6,657,461
6,423,611	6,658,716
6,423,645	6,660,592
6,426,016	6,663,720
6,426,500	6,670,267
6,440,796	6,693,005

ASSIGNMENT

Per the Assignment Agreement entered on December 23, 2003 ("Date of Agreement") between Mosel Vitelic, Inc. ("Assignor"), a Taiwan Corporation, and ProMOS Technologies Inc. ("Assignee"), a Taiwan Corporation having a place of business at 3F, No. 19, Li-Hsin Road, Science-Based Industrial Park, Hsin Chu City, Taiwan, and effective on the Date of Agreement, the Assignor irrevocably sells, assigns, conveys, grants and transfers, and agrees to sell, assign, convey, grant and transfer, and cause to be sold, assigned, conveyed, granted and transferred, to the Assignee, its successors and permitted assigns any and all of the Assignor's rights, titles, interests, benefits, claims and liabilities of every kind and character, in and to the patents listed in the attached Schedule A, to the full extent of the Assignor's ownership or interest therein; including, without limitation, all rights to causes of action and remedies related thereto (including, without limitation, the right to sue for past, present or future infringement, misappropriation or violation of rights related to the foregoing); and any and all other rights and interests arising out thereof, in connection therewith or in relation thereto. To the extent that any terms of this Assignment may be inconsistent with any terms of the Assignment Agreement, the Assignment Agreement shall control.

Executed this 27 day of April, 2004

Mosel Vitelic, Inc.

John W. Seto
(Signature)

JOHN W. SETO
(Please Print or Type Name)

Executive Vice President
(Please Print or Type Title)

State of California)
) ss.
County of: Santa Clara)

On 04/27/04, before me, Nonna Pikiner, Notary Public personally appeared JOHN W. SETO personally known to me or proved to me on the basis of satisfactory evidence to be the person(s) whose name(s) is(are) subscribed to the within instrument and acknowledged to me that he/she/they executed the same in his/her/their authorized capacity(ies), and that by his/her/their signature(s) on the instrument the person(s), or the entity upon behalf of which the person(s) acted, executed this instrument.

WITNESS my hand and official seal.

NONNA PIKINER
Commission # 1364722
Notary Public - California
Santa Clara County
My Comm. Expires Aug 11, 2006

Nonna Pikiner
SIGNATURE OF NOTARY

SCHEDULE A
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Number	Issued	Filed	Patent	Inventors
4,868,617	9/19/89	4/25/88	Gate Controllable Lightly Doped Drain MOSFET Devices	Chiao et al
4,888,734	12/19/89	12/28/87	EPROM / Flash EEPROM Cell and Array Configuration	Lee et al
4,888,735	12/19/89	4/28/88	ROM Cell and Array Configuration	Lee et al
5,148,056	9/15/92	3/27/91	Output Buffer Circuit	Glass et al
5,192,916	3/9/93	9/20/91	Charge-Pump Phase Locked Loop Circuit	Glass
5,327,026	7/5/94	2/17/93	Self-Timed Bootstrap Decoder	Hardee et al
5,345,195	9/6/94	10/22/92	Low Power Vcc and Temperature Independent Osc...	Cordoba et al
5,347,171	9/13/94	10/15/92	Efficient Negative Charge Pump	Cordoba et al
5,347,172	9/13/94	10/22/92	Oscillatorless Substrate Bias Generator	Cordoba et al
5,373,470	12/13/94	3/26/93	Method and Circuit for Configuring I/O Devices	Jones
5,412,257	5/2/95	10/20/92	High Efficienct N-Channel Charge Pump ...	Cordoba et al
5,430,680	7/4/95	10/12/93	DRAM having Self-Timed Burst Refresh Mode	Parris
5,438,287	8/1/95	6/1/94	High Speed Differential Current Sense Amplifier ...	Faue
5,440,246	8/8/95	3/22/94	Programmable Circuit with Fusible Latch	Murray et al
5,461,590	10/24/95	7/7/94	Low Power VCC and Temperature Independent Osc...	Cordoba et al
5,481,581	1/2/96	5/19/95	Programmable Binary / Interleave Sequence Counter	Jonas
5,514,609	5/7/96	5/13/94	Through glass ROM code implant . . .	Chen et al
5,516,711	5/14/96	12/16/94	Method for Forming LDD CMOS with Oblique Implantation	Wang
5,547,882	8/20/96	10/11/95	Method for Forming Retrograde Channel Profile ...	Juang et al
5,606,191	2/25/97	4/14/95	Semiconductor device with LDD regions, Div 12/16/94	Wang
5,643,632	7/1/97	10/13/95	Tungsten CVD Process for Suppression of Volcano Formation	Lo
5,644,545	7/1/97	2/14/96	Bimodal Refresh Circuit and Method ...	Fisch
5,646,074	7/8/97	12/15/95	Method of Forming Gate Oxide for FET	Chen et al
5,650,341	7/22/97	10/3/96	Process for Fabricating CMOS Device	Yang et al
5,663,915	9/2/97	6/7/95	Amplifier and Method for Sensing ...	Mobley
5,671,392	9/23/97	4/11/95	Memory Device Circuit and Method ...	Parris et al
5,672,243	9/30/97	11/28/95	Antireflection Coating for Highly Reflective ... Layers ...	Hsia et al
5,679,595	10/21/97	7/24/96	Self Registered Capacitor Bottom Plate ...for DRAM	Chen et al
5,681,772	10/28/97	5/30/96	Through Glass ROM Code Implant . . .	Chen et al

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Number	Issued	Filed	Patent	Inventors
5,686,324	11/11/97	3/28/96	Process for Forming LDD CMOS using Large-Tilt-Angle II	Wang et al
5,691,223	11/25/97	12/20/96	Method of Fabricating a Capacitor over a Bit Line . . .	Pittikoun et al
5,691,240	11/25/97	11/20/96	Method for Forming Blanket Planarization . . .	Yang
5,691,562	11/25/97	4/13/95	Through Glass ROM Code Implant . . ., Div 5/13/94	Chen et al
5,696,016	12/9/97	11/15/96	Process for Manufacturing a CMOSFET Int. Circuit	Chen et al
5,696,036	12/9/97	11/15/96	DRAM NO Capacitor Dielectric Process	Su et al
5,698,903	12/16/97	5/9/95	Bond Pad Option for Integrated Circuits	Parris et al
5,701,013	12/23/97	6/7/96	Wafer Metrology Pattern integrating . . .	Hsia et al
5,703,388	12/30/97	7/19/96	Double poly MONOS flash EEPROM cell	Wang et al
5,724,825	3/10/98	9/11/96	Automatic Temperature Controlling System	Lee et al
5,726,086	3/10/98	11/18/96	Method of Making Self-Aligned Cylindrical Capacitor . . .	Wu
5,728,598	3/17/98	7/24/96	Method of Manufacturing a SRAM Cell . . .	Wu et al
5,733,114	3/31/98	1/28/97	Detachible Torch for Wet Oxidation	Peng et al
5,747,357	5/5/98	9/27/95	Modified Poly-Buffered Isolation	Su
5,747,368	5/5/98	10/3/96	Process for manufacturing CMOS device	Yang et al
5,747,378	5/5/98	5/27/97	Method of Damage Free Doping for Forming a DRAM .. Cell	Fan et al
5,760,484	6/2/98	2/11/97	Alignment mark pattern for semiconductor process	Lee et al
5,770,515	6/23/98	12/12/96	Method of in-situ wafer cooling . . .	Meng et al
5,776,833	7/7/98	9/4/96	Method for forming metal plug	Chen et al
5,783,473	7/21/98	1/6/97	Structure ... process of a split gate flash memory unit	Sung
5,788,567	8/4/98	2/16/96	Apparatus for guiding air current . . .	Chang et al
5,789,267	8/4/98	8/23/96	Method of making corrugated cell contact	Hsia et al
5,789,296	8/4/98	12/5/96	Method for manufacturing split gate flash memory	Sung et al
5,789,297	8/4/98	10/24/96	Method of making EEPROM cell device . . .	Wang et al
5,792,686	8/11/98	2/7/96	Method of forming a bit-line and a capacitor structure …	Chen et al
5,804,091	9/8/98	7/18/96	Method of preventing defects and particles …	Lo et al
5,804,493	9/8/98	10/11/95	Method for preventing substrate damage . . .	Juang et al
5,811,344	9/22/98	1/27/97	Method of forming a capacitor of a DRAM cell	Tu et al
5,811,358	9/22/98	1/3/97	Low temperature dry process for stripping photoresist …	Tseng et al

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Number	Issued	Filed	Patent	Inventors
5,811,864	9/22/98	3/15/96	Planarized Integrated Circuit Product and Method ...	Butler
5,818,291	12/6/98	4/4/97	Fast Voltage Regulation without Overshoot	Tiede, Faue
5,821,564	10/13/98	5/23/97	TFT with self-align offset gate	Wu et al
5,824,234	10/20/98	10/2/96	Method for forming low contact resistsance bonding pad	Jou et al
5,824,578	10/20/98	12/12/96	Method of making a CMOS transistor ...	Yang
5,827,747	10/27/98	3/28/96	Method for forming LDD CMOS using double spacers ...	Wang et al
5,827,780	10/27/98	4/1/96	Additive metalization using photosensitive polymer . . .	Hsia et al
5,827,783	10/27/98	8/23/96	Stacked capacitor having improved charge storage ...	Hsia et al
5,837,578	11/17/98	7/16/97	Process of manufacturing a trenched stack-capacitor	Fan et al
5,841,718	11/24/98	8/8/97	Use of voltage equilization in signal-sensing circuits	Watters et al
5,843,822	12/1/98	2/5/97	Double-side corrugated cylindrical capacitor structure ...	Hsia et al
5,851,867	12/22/98	8/27/96	Rugged stacked oxide layer structure and method ...	Chen et al
5,851,898	12/22/98	8/23/96	Method ... stacked capacitor having corrugated side-wall ...	Hsia et al
5,851,900	12/22/98	4/28/97	Method of manufacturing a shallow trench isolation ...	Chu et al
5,852,573	12/22/98	10/8/97	Polyload SRAM memory cell with low standby current	Yang et al
5,858,867	1/12/99	5/20/96	Method of making an inverse-T tungsten gate	Hsia et al
5,869,394	2/9/99	10/29/96	TEOS-ozone planarization process	Chen et al
5,869,399	2/9/99	8/7/97	Method for increasing utilizable surface of rugged ...	Tu et al
5,869,406	2/9/99	9/28/95	Method for forming insulating layers between poly ...	Su et al
5,877,073	3/2/99	5/7/96	Modified poly-buffered LOCOS ...	Mao et al
5,877,638	3/2/99	9/18/96	Output buffer with low noise and high drive ... CIP 5/23/95	Lin
5,879,988	3/9/99	6/12/96	Capacitor of a DRAM cell and method of making same	Chen et al
5,880,496	3/9/99	7/14/97	Semiconductor having self-aligned polysilicon ...	Chen et al
5,882,984	3/16/99	10/9/96	Method for increasing the refresh time of the DRAM	Fan et al
5,883,015	3/16/99	7/3/97	Method for using oxygen plasma treatment ...	Liao et al
5,885,866	3/23/99	6/11/97	Self-registered cylindrical capacitor of high density DRAMs	Chen
5,892,232	4/6/99	10/25/96	Arc chamber for ion implanter	Tsai et al
5,908,659	6/1/99	1/3/97	Method for reducing the reflectivity of a silicide layer	Lo et al
5,909,621	6/1/99	2/5/97	Single-side corrugated cylindrical capacitor structure ...	Hsia et al

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Number	Issued	Filed	Patent	Inventors
5,917,214	6/29/99	2/26/98	Split gate flash memory unit	Sung
5,920,780	7/6/99	1/31/97	Method of forming a self aligned contact (SAC) window	Wu
5,926,712	7/20/99	11/21/96	Process for fabricating MOS device having short channel	Chen et al
5,926,715	7/20/99	6/4/97	Method of forming LDD by automatic PSG doping	Fan et al
5,930,593	7/27/99	7/16/97	Method of formating device on wafer without peeling	Tsai et al
5,930,631	7/27/99	6/12/97	Method of making double-poly MONOS flash EEPROM ...	Wang et al
5,934,974	8/10/99	11/5/97	In-situ monitoring of polishing pad wear	Tzeng
5,937,907	8/17/99	6/18/96	Manifold having outlets equally spaced from inlet	Lee
5,942,041	8/24/99	9/16/96	Non-sticking semiconductor wafer clamp and method ...	Lo et al
5,946,568	8/31/99	5/17/96	Self-aligned method of fabricating a DRAM with improved cap.	Hsiao et al
5,947,802	9/7/99	11/5/97	Wafer shuttle system	Zhang et al
5,957,764	9/28/99	11/5/97	Modular wafer polishing apparatus and method	Anderson et al
5,960,279	9/28/99	8/27/96	Method of fabricating a capacitor on a rugged stacked ...	Chen et al
5,963,806	10/5/99	8/19/97	Method of forming memory cell with built-in erasure ...	Sung et al
5,963,830	10/5/99	10/27/97	Method of forming a TiN/W barrier layer for a hot Al plug	Wang et al
5,964,413	10/12/99	11/5/97	Apparatus for dispensing slurry	Mok
5,965,462	10/12/99	10/27/97	Method for forming a gate structure ...	Tan et al
5,966,626	10/12/99	11/7/96	Method for stabilizing a silicon structure after ion implant	Lo et al
5,966,632	10/12/99	1/21/97	Method of forming borderless metal to contact structure	Chen et al
5,970,360	10/19/99	12/3/96	DRAM cell with roughened poly-Si electrode	Cheng et al
5,972,746	10/26/99	10/8/96	Method for manufacturing semiconductor devices ...	Wang et al
5,972,754	10/26/99	6/10/98	Method for fabricating MOSFET ...	Ni et al
5,973,980	10/26/99	7/23/98	Fast voltage regulation without overshoot	Tiede et al
5,977,608	11/2/99	2/11/97	Modified poly-buffered isolation	Su
5,980,368	11/9/99	11/5/97	Polishing tool having a sealed fluid chamber ...	Chang et al
5,986,474	11/16/99	1/12/96	Data line bias circuit	Chung et al
5,989,971	11/23/99	9/9/97	Method for forming trenched polysilicon structure	Tu et al
6,000,997	12/14/99	7/10/98	Temperature regulation in a CMP process	Kao et al
6,001,697	12/14/99	3/24/98	Process for manufacturing semiconductor devces ...	Chang et al

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Number	Issued	Filed	Patent	Inventors
6,001,745	12/14/99	4/14/98	Method for forming a via in an inter metal dielectric (IMD) ...	Tu et al
6,008,106	12/28/99	8/21/97	Micro-trench oxidation by using rough oxide mask ...	Tu et al
6,008,515	12/28/99	5/6/98	Stacked capacitor having improved charge storage ...	Hsia et al
6,008,688	12/28/99	3/30/98	Apparatus and ... method for preventing ... latch-up ...	Faue
6,010,938	1/4/00	11/11/98	Method of making a load resistor on a ... chip	Wang et al
6,010,944	1/4/00	4/14/98	Method for increasing capacity of a capacitor	Huang et al
6,017,816	1/25/00	2/25/97	Method of fabricating A1N antireflection coating ...	Ni et al
6,019,664	2/1/00	3/31/99	Height gauge device for water	Tsai et al
6,020,231	2/1/00	3/18/97	Method for forming LDD CMOS	Wang et al
6,020,259	2/1/00	5/1/97	Method of forming a tungsten plug contact ...	Chen et al
6,025,245	2/15/00	5/18/99	Method of forming a trench capacitor with a sacrificial ...	Wei
6,025,981	2/15/00	11/4/98	Flexible voltage transient detector circuit	Wu
6,027,761	2/22/00	10/14/98	Manufacturing process and structure of capacitor	King
6,030,893	2/29/00	12/6/96	Chemical vapor deposition of tungsten (W-CVD) process ...	Lo et al
6,031,407	2/29/00	7/7/94	Low power circuit for detecting a slow ... Input, Div.10/22/92	Cordoba et al
6,037,208	3/14/00	4/26/99	Method for forming a deep trench capacitor in a DRAM ...	Wei
6,037,251	3/14/00	1/6/98	Process for intermetal SOG/SOP dielectric planarization	Tu et al
6,037,624	3/14/00	8/11/98	Process and structure of a modified T-shaped capacitor ...	King
6,040,216	3/21/00	2/5/98	Method (and device) for producing tunnel silicon ...	Sung
6,042,457	3/28/00	7/10/98	Conditioner assembly for a CMP aqpparatus	Wilson et al
6,043,547	3/28/00	6/6/97	Circuit structure with an anti-reflective layer	Hsia et al
6,044,018	3/28/00	6/17/98	Single-poly flash memory cell for embedded ...	Sung et al
6,046,092	4/4/00	10/4/98	Method for manufacturing a capacitor	Chang
6,054,350	4/25/00	4/2/98	EPROM cell having a gate structure with sidewall ...	Hsieh et al
6,057,197	5/2/00	5/20/98	Isolation scheme to prevent field oxide edge from ...	Sung
6,057,576	5/2/00	9/24/98	Inverse-T tungsten gate apparatus	Hsia et al
6,059,643	5/9/00	2/21/97	Apparatus and Method for Polishing a Flat Surface ...	Hu et al
6,062,959	5/16/00	11/5/97	Polishing System including a Hydrostatic Fluid ...	Weldon et al
6,062,961	5/16/00	11/5/97	Wafer Polishing Head Drive	Can et al

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6,066,529	5/23/00	11/23/98	Method for enlarging surface area of a plurality ...	Lin et al
6,069,052	5/30/00	10/7/96	Process and structure for increasing capacitance ...	Wu
6,069,088	5/30/00	3/11/99	Method for prolonging lifetime of a plasma etching ...	Chiang et al
6,071,794	6/6/00	6/1/99	Method to prevent the formation of a thinner portion ...	Lin et al
6,074,291	6/13/00	2/16/99	Apparatus for preparing ultra-thin specimen	Chang et al
6,077,737	6/20/00	6/2/98	Method for forming a DRAM having improved capacitor ...	Yang et al
6,080,040	6/27/00	11/5/97	Wafer Carrier Head with Inflatable Bladder ...	Appel et al
6,080,595	6/27/00	2/19/99	Method for estimating the thickness of layer ...	Li
6,080,627	6/27/00	7/12/99	Method for forming a trench power metal-oxide ...	Fan et al
6,083,792	7/4/00	12/30/96	Manufacturing process of a split gate flach memory unit	Sung
6,084,803	7/4/00	10/23/98	Initializion of non-volatile programmable latches ...	Sredanovic et al
6,086,456	7/11/00	11/6/98	Polishing method using a hydrostatic fluid ...	Weldon et al
6,088,270	7/11/00	8/2/94	Sense Amplifier with Local Write Drivers	Hardee
6,090,680	7/18/00	10/14/98	Manufacturing process for a capacitor	Chang
6,090,725	7/18/00	8/30/99	Method for preventing bubble defects in BPSG film	Yang et al
6,093,627	7/25/00	5/12/98	Self-aligned contact process using silicon spacers	Sung
6,096,645	8/1/00	3/4/98	Method of making IC devices having a stable CVD ...	Lo et al
6,098,901	8/8/00	7/10/98	Apparatus for dispensing slurry	Mok et al
6,099,386	8/8/00	6/28/99	Control device for maintaining a CMP machine ...	Tsai et al
6,100,126	8/8/00	5/21/97	Method of making a resistor utilizing a polysilicon plug ...	Chen et al
6,100,561	8/8/00	7/14/98	Method for forming LDD CMOS using double spacers ...	Wang et al
6,107,193	8/22/00	2/12/98	Completely removal of TiN residue ...	Shiao et al
6,110,801	8/29/00	11/13/98	Method of fabricating trench isolation for IC manufacture	Tsai et al
6,110,810	8/29/00	7/2/98	Process for forming N-channel through amorphous silicon ...	Chen et al
6,113,736	9/5/00	4/2/99	Gas ring apparatus for semiconductor etching	Lan et al
6,114,209	9/5/00	3/19/98	Method of fabricating semiconductor devices ...	Chu et al
6,117,727	9/12/00	7/15/98	Manufacturing process of capacitor	King
6,117,755	9/12/00	7/24/98	Method for planarizing the interface of polysilicon ...	Kun-Yu et al
6,117,780	9/12/00	4/22/99	Chemical mechanical polishing method ...	Tsai et al

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6,121,107	9/19/00	10/15/98	Manufacturing process and structure of capacitor	Chang
6,121,116	9/19/00	3/12/98	Flash memory device isoLation method and structure	Sung
6,124,178	9/26/00	8/26/99	Method of manufacturing MOSFET devices	Sung et al
6,126,512	10/3/00	7/10/98	Robust belt tracking and control system ...	Chao et al
6,126,527	10/3/00	7/10/98	Seal for polishing belt center support ...	Kao et al
6,127,075	10/3/00	10/1/98	Method for checking accuracy of a measuring instrument ...	Hsu et al
6,127,699	10/3/00	8/10/99	Method for fabricating MOSFET having increased ...	Ni et al
6,128,070	10/3/00	5/12/99	Monitor method and apparatus for overlay alignment ...	Peng
6,128,236	10/3/00	12/17/98	Current Sensing Differential Amplifier ...	Faue et al
6,130,433	10/10/00	5/3/99	Ion source chamber of a high energy implanter ...	Tsai et al
6,133,155	10/17/00	11/23/98	Method for preventing corrosion of a metallic layer ...	Tsai-Sen et al
6,133,597	10/17/00	7/25/97	Biasing an integrated circuit well	Li et al
6,136,647	10/24/00	5/14/97	Method of forming interpoly dielectric and gate oxide ...	Sung
6,136,653	10/24/00	5/11/98	Method and device for producing undercut gate ...	Sung et al
6,144,059	11/7/00	8/17/99	Process and structure for increasing capacItance ...	Wu
6,146,249	11/14/00	10/22/98	Apparatus and method for polishing a flat surface ...	Hu et al
6,146,997	11/14/00	9/29/99	Method for forming self-aligned contact hole	Liu et al
6,147,013	11/14/00	1/26/99	Method of LPCVD silicon nitride deposition	Sun et al
6,149,078	11/21/00	12/6/99	Slurry nozzle	Tsai et al
6,149,512	11/21/00	11/6/97	Linear pad conditioning apparatus	Wilson et al
6,150,238	11/21/00	5/17/99	Method for fabricating a trench isolation	Wu et al
6,150,244	11/21/00	12/10/99	Method for fabricating MOS transistor ...	Ni
6,153,462	11/28/00	8/11/98	Manufacturing process and structure of capacitor	King
6,153,907	11/28/00	12/21/98	IC layout structure for MOSFET ...	Huang et al
6,159,083	12/12/00	7/15/98	Polishing head for a CMP apparatus	Appel et al
6,160,743	12/12/00	3/21/00	Self-timed data amplifier ...	Parris
6,162,724	12/19/00	4/13/98	Method for forming metalization for inter-layer connections	Hsia et al
6,163,492	12/19/00	10/23/98	Programmable latches that include non-volatile ...	Sredanovic et al
6,165,843	12/26/00	3/20/98	Covered slit isolation between integrated circuit devices	Sung

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6,171,904	1/9/01	7/14/99	Method for forming rugged polysilicon capacitor	Lin et al
6,171,927	1/9/01	6/8/98	device with differential field isolation thicknesses … methods	Sung et al
6,172,554	1/9/01	9/24/98	Power supply insensitive substrate bias voltage det…	Young et al
6,180,980	1/30/01	8/18/99	Trench non-volatile memory cell	Wang
6,184,092	2/6/01	11/23/99	Self-aligned contact for trench DMOS transistors	Tseng et al
6,184,093	2/6/01	8/21/98	Method of implementing differential gate oxide thick…	Sung
6,185,159	2/6/01	8/5/99	Radio control alarm device	Sun et al
6,188,072	2/13/01	6/8/99	Apparatus for extracting TEM specimens …	Chung
6,190,928	2/20/01	9/3/98	Method for actually measuring misalignment of via	Lo et al
6,190,990	2/20/01	1/13/99	Method for manufacturing the storage node of a cap …	Wei
6,191,003	2/20/01	1/19/00	Method for planarizing a polycrystalline silicon layer …	Lin et al
6,191,986	2/20/01	5/10/00	Memory device with redundancy arrays	Hsu et al
6,191,997	2/20/01	3/10/00	Memory burst operations …	Son et al
6,194,269	1/27/01	3/6/98	Method to improve cell performance in split gate flash EEPROM	Sung et al
6,194,272	2/27/01	5/19/98	Split gate flash cell with extremely small cell size	Sung
6,195,302	2/27/01	1/27/00	Dual slope sense clock generator (UMI 216)	Hardee
6,197,659	3/6/01	11/19/99	Divot free shallow trench isolation process	Liu
6,201,413	3/13/01	10/1/98	Synchronous integrated circuit device … (UMI 221)	Faue
6,204,547	3/20/01	6/22/99	Modified poly-buffered isolation	Su
6,204,677	3/20/01	9/22/98	Contact pressure jig for signal analysis	Hallgren
6,208,574	3/27/01	5/2/95	Sense amplifier with local column read amplifier …	Hardee et al
6,218,267	4/17/01	11/11/98	Shallow trench isolation method …	Liu
6,218,275	4/17/01	9/27/99	Process for forming self-aligned contact …	Huang et al
6,222,776	4/24/01	9/25/00	Programmable latches that include non-volatile …D2	Sredanovic et al
6,228,661	5/8/01	4/27/00	Method to Determine the Dark-to-Clear Exposure Dose …	Li
6,228,729	5/8/01	2/25/00	MOS transistors having raised source and drain and interconnects	Ni
6,228,776	5/8/01	12/7/99	Ashing process by adjusting etching endpoint …	Chiang
6,232,199	5/15/01	6/7/00	Method for Forming a Multi-Cylinder Capacitor	Wei
6,235,592	5/22/01	9/21/99	Type of high density vertical mask ROM cell	Sung

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6,235,604	5/22/01	7/16/98	Manufacturing process for a capacitor	King
6,236,327	5/22/01	2/18/99	Wafer-fetching sensing device for wafer storage apparatus	Yen et al
6,240,034	5/29/01	9/25/00	Programmable latches that include non-volatile ...D3	Sredanovic et al
6,241,597	6/5/01	3/9/99	Cleaning apparatus for maintaining semiconductor equipment	Chiang et al
6,242,357	6/5/01	5/6/99	Method for forming a deep trench capacitor of a DRAM cell	Wei et al
6,242,365	6/5/01	6/4/99	Method for preventing film deposited on semiconductor wafer ...	Chu et al
6,242,774	6/5/01	3/11/99	Poly spacer split gate cell with extremely small cell size	Sung
6,244,945	6/12/01	6/1/00	Polishing system including a hydrostatic fluid ...	Weldon et al
6,245,148	6/12/01	4/28/99	SOG dispensing system and its controlling sequences	Liang et al
6,245,467	6/12/01	8/17/99	Patterned mask and deep trench capacitor formed thereby	Peng et al
6,245,608	6/12/01	6/14/99	Ion implantation process for forming contact regions ...	Lin et al
6,245,643	6/12/01	4/30/99	Method of removing polysilicon residual in a LOCOS isolation ...	King et al
6,249,469	6/19/01	11/12/92	Sense amplifier with local sense drivers and local read amplifiers	Hardee
6,251,722	6/26/01	4/11/00	Method of Fabricating a Trench Capacitor	Wei et al
6,255,188	7/3/01	3/8/99	Method of removing a polysilicon buffer using an etching selectivity ...	Chen et al
6,255,205	7/3/01	6/8/98	High density programmable Read-Only Memory ...	Sung
6,261,893	7/17/01	10/12/00	Method for Forming a Magnetic Layer of Magnetic RAM	Chang et al
6,261,903	7/17/01	5/14/98	Floating gate method and device	Chang et al
6,261,926	7/17/01	5/11/00	Method for Fabricating Field Oxide	King
6,261,930	7/17/01	4/7/99	Method for forming a hemispherical-grain polysilicon	Lin et al
6,261,966	7/17/01	8/12/99	Method for improving trench isolsation	Li et al
6,265,233	7/24/01	6/4/99	Method for determining crack limit of film deposited on semi ...	Chu et al
6,265,269	7/24/01	8/6/99	Method for fabricating a concave bottom oxide in a trench	Chen et al
6,265,754	7/24/01	10/13/00	Covered Slit Isolation between Integrated Circuit Devices	Sung
6,266,266	7/24/01	8/31/00	Integrated circuit design exhibiting reduced capacity	Aldrich et al
6,266,290	7/24/01	3/1/00	Programmable latches that include non-volatile ...D1	Sredanovic et al
6,267,655	7/31/01	7/15/98	Retaining ring for wafer polishing	Weldon et al
6,271,079	8/7/01	5/19/99	Method of forming a trench capacitor	Wei et al
6,271,556	8/7/01	1/14/98	High density memory structure	Chen et al

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6,273,953	8/14/01	9/21/99	Piping system for etch equipment	Yeh et al
6,273,962	8/14/01	4/6/99	Method to reduce the particles in load-lock chamber	Wu et al
6,274,509	8/14/01	1/28/99	Global planarization method	Hsieh et al
6,275,432	8/14/01	11/12/92	Method of reading and writing data ... (UMI 109 D3)	Hardee
6,284,578	9/4/01	3/24/00	MOS transistors having dual gates and self-aligned interconnect ...	Ni
6,291,827	9/18/01	3/26/99	Insulating apparatus for a conductive line	Tsai et al
6,297,088	10/2/01	6/2/00	Method for forming a deep trench capacitor in a DRAM cell	King
6,299,218	10/9/01	3/4/99	Connecting structure between fluid chanel	Tsai et al
6,299,788	10/9/01	3/29/99	Silicon etching process	Wu et al
6,303,436	10/16/01	9/21/99	Method for fabricating a type of trench mask ROM cell	Sung
6,310,688	10/30/01	8/10/98	Method for measuring the parameter of a rough film	Kao et al
6,315,857	11/13/01	7/10/98	Polishing pad shaping and patterning	Cheng et al
6,319,795	11/20/01	1/5/00	Method for fabricating VLSI devices having trench isolation regions	Liu
6,322,429	11/27/01	7/10/98	Conditioner assembly ... for a CMP apparatus	Wilson et al
6,324,097	11/27/01	8/26/99	Single poly non-volatile memory structure and ... method	Chen et al
6,326,320	12/4/01	6/29/00	Method for forming oxide layer on conductor plug ...	Yang et al
6,326,574	12/4/01	9/21/99	Sleeve for an adapter flange of the gasonics L3510 etcher	Huang et al
6,331,721	12/18/01	3/5/99	Memory cell with built in erasure feature	Sung et al
6,332,275	12/25/01	2/12/99	Margin inspector for IC wafers	Tsai et al
6,334,258	1/1/02	8/23/99	Inspection device for examining a piece of aperture graphite ...	Lee et al
6,335,260	1/1/02	3/23/00	Method for improving the dimple phenomena of a polysilicom film ...	Tseng et al
6,336,787	1/8/02	10/7/99	Method for transferring wafers in a semiconductor ... apparatus	Chang et al
6,337,278	1/8/02	8/23/00	Technique for forming a borderless overlapping gate ...	Butler
6,337,830	1/8/02	8/31/00	Integrated clocking latency ... for DDR SDRAM ...	Faue
6,339,354	1/15/02	4/3/02	System and method for eliminating pulse width variations ...	Heightly
6,342,426	1/29/02	2/8/01	Method for protecting stepper alignment marks	Li et al
6,346,418	2/12/02	6/25/99	Method for evaluation of metal impurity in lithographic materials	Chang et al
6,346,474	2/12/02	12/13/99	Dual damascene process	Liu
6,346,839	2/12/02	4/3/00	Low power consumption IC delay locked loop ...	Mnich

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6,352,908	3/5/02	3/3/00	Method for reducing nitride residue in a LOCOS isolation area	King et al
6,355,524	3/12/02	8/15/00	Nonvolatile memory structures and fabrication methods	Tuan et al
6,355,974	3/12/02	5/31/00	Method to prevent the formation of a thinner portion of isolating layer …	Lin et al
6,358,676	3/19/02	10/22/99	Method for reworking photoresist	Wu
6,358,864	3/19/02	5/3/99	Method of fabricating an oxide/nitride multilayer structure …	Chang et al
6,359,487	3/19/02	4/3/00	System … of compensating for non-linear voltage-to-delay …	Heightly et al
6,365,064	4/2/02	10/15/98	Method for evenly immersing a wafer in a solution	Tsai et al
6,365,455	4/2/02	6/5/98	Flash memory process using polysilicon spacers	Su et al
6,365,524	4/2/02	4/8/99	Method for making a concave bottom oxide within a trench	Chen et al
6,368,882	4/9/02	11/1/99	Method for detecting organic contamination …	Chang et al
6,373,778	4/16/02	1/28/00	Burst operation in memories	Song et al
6,374,833	4/23/02	5/5/99	Method of in situ reactive gas plasma treatment	Yuan et al
6,375,194	4/23/02	8/23/96	Method for semiconductor wafer processing system	Peng
6,376,300	4/23/02	11/10/99	Process of manufacturing trench capacitor …	Chang
6,380,072	4/30/02	8/4/98	Metallizing process of semiconductor industry	Chu et al
6,384,482	5/7/02	11/3/00	Method for forming a dielectric layer in a semiconductor device …	Yang et al
6,386,139	5/14/02	8/12/99	Wafer load/unload apparatus for e-gun evaporation process	Hung et al
6,386,213	5/14/02	8/20/99	Plate-tilting apparatus	Hung et al
6,388,265	5/14/02	11/2/98	Method for distinguishing a specific region in a sample …	Chang et al
6,391,739	5/21/02	7/19/00	Process of eliminating a shallow trench isolation divot	Liao
6,392,304	5/21/02	11/12/98	Multichip memory apparatus and associated method	Butler
6,397,480	6/4/02	7/6/00	Mechanism for sharpening a writing instrument	Mak et al
6,399,437	6/4/02	6/18/98	Enhanced sidewall stacked capacitor	Hsu et al
6,399,980	6/4/02	2/27/98	Fabrication of a T-shaped capacitor	King
6,403,489	6/11/02	1/31/00	Method for removing polymer stacked on a lower electrode …	Yuan et al
6,406,209	6/18/02	3/24/00	Upper lid alignment apparatus for hatchback reaction cabin	Liu et al
6,406,953	6/18/02	7/25/97	Method for fabricating an IC with a transistor electrode	Li et al
6,414,350	7/2/02	12/14/99	EPROM cell having a gate structure with dual side-wall …	Hsieh et al
6,415,374	7/2/02	3/16/00	System and method for supporting sequential burst counts …	Faue et al

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6,417,099	7/9/02	9/3/98	Method for controlling dopant diffusion in a ... polysilicon layer ...	Tsai et al
6,423,611	7/23/02	4/20/00	Manufacturing process of capacitor	King
6,423,645	7/23/02	6/27/00	Method for forming a self-aligned contact	Wei et al
6,426,016	7/30/02	8/6/99	Method for etching passivation layers and antireflective layer ...	Yang et al
6,426,500	7/30/02	11/1/99	Method for protecting a specific region in a sample ...	Chang et al
6,440,796	8/27/02	3/30/01	Poly spacer split gate cell with extremely small cell size	Sung
6,445,621	9/3/02	4/11/00	Dynamic data amplifier with built-in voltage level shifting	Heightly
6,454,641	9/24/02	11/7/00	Hydrosatatic fluid bearing support with adjustable inlet heights	Weldon et al
6,465,369	10/15/02	1/21/00	Method for stabilizing semiconductor degas temperature	Teng et al
6,469,341	10/22/02	7/25/00	Method and device for producing undercut gate for Flash memory	Sung, Lee
6,469,559	10/22/02	11/8/01	System and method for eliminating pulse width variations ...	Heightley
6,491,178	12/10/02	11/15/00	Upper cover plate for an air-tight chamber and a tool for ...	Liu et al
6,492,188	12/10/02	3/11/99	Monitor method for quality of metal ARC layer	Lin et al
6,492,248	12/10/02	6/26/01	Few-particle-induced low-pressure TEOS process	Chang et al
6,492,263	12/10/02	10/6/00	Dual damascene process which prevents diffusion of metals ...	Peng et al
6,500,712	12/31/02	6/17/02	Fabrication of dielectric in trenches formed in a ... substrate ...	Wu
6,503,824	1/7/03	10/12/01	Forming conductive layers on insulators by physical vapor deposition	Fortin
6,506,615	1/14/03	2/11/02	Method for measuring the depth of well	Chen et al
6,509,198	1/21/03	10/4/01	Method of power IC inspection	Jaw et al
6,515,327	2/4/03	10/18/00	Trench capacitor with expanded area and method ...	King
6,531,387	3/11/03	6/17/02	Polishing of conductive layers in fabrication of integrated circuits	Wu
6,538,455	3/25/03	5/25/01	Coupling for a reflectivity measuring device	Shieh et al
6,543,980	4/8/03	5/24/01	Teaching tool for a robot arm for wafer reaction ovens	Lin et al
6,544,847	4/8/03	7/26/01	Single poly non-volatile memory structure and its fabrication method	Chen et al
6,551,900	4/22/03	4/12/00	Trench gate oxide formation method	Chung et al
6,559,055	5/6/03	4/30/01	Dummy structures that protect circuit elements during polishing	Tuan et al
6,562,681	5/13/03	1/13/01	Nonvolatile memories with floating gate spacers, ...	Tuan et al
6,563,166	5/13/03	3/10/00	Flash cell device	Ni
6,563,747	5/13/03	9/18/01	Integrated data input sorting and timing circuit ...	Faue

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6,566,196	5/20/03	5/15/02	Sidewall protection in fabrication of integrated circuits	Haselden et al
6,568,988	5/27/03	7/28/00	Chemical mechanical polishing apparatus with stable signals	Chin et al
6,570,215	5/27/03	7/18/02	Nonvolatile memories with floating gate spacers, and methods ...	Tuan et al
6,571,488	6/3/03	3/1/02	System for sensing position of spin dryer cover	Lin et al
6,584,018	6/24/03	10/5/01	Nonvolatile memory structures and access methods	Tuan et al
6,584,578	6/24/03	3/14/00	Arbitration method and circuit for control of ... DDR ...	Faue
6,597,201	7/22/03	8/29/00	Dynamic predecoder circuitry fo memory circuits	Parris et al
6,606,088	8/12/03	10/3/00	LCD panel signal processor	Yang et al
6,613,672	9/2/03	7/25/00	Apparatus and process of fabricating a trench capacitor	Wang et al
6,617,636	9/9/03	9/14/01	Nonvolatile memory structures and fabrication methods	Tuan et al
6,621,747	9/16/03	11/4/02	Integrated data input sorting and timing circuit for DDR ...	Faue
6,632,685	10/14/03	6/28/01	Apparatus and method for determining various processes ...	Chiu et al
6,643,186	11/4/03	10/9/01	Nonvolatile memory structures and fabrication methods	Tuan et al
6,645,808	11/11/03	10/15/02	Method and device for providing double cell density in SDRAM ...	Tsai
6,647,607	11/18/03	2/11/02	Auxiliary tool for assembling a scrubber	Chen et al
6,654,291	11/25/03	5/24/02	Electrically erasable programmable read-only memory ...	Jan et al
6,657,263	12/2/03	6/28/01	MOS transistors having dual gates and self-aligned interconnect ...	Ni
6,657,461	12/2/03	3/22/01	S&M for high speed integrated circuit device testing ...	Jones et al
6,658,716	12/9/03	3/25/02	Method for sassembling motor assembly to support wafer	Tai et al
6,660,592	12/9/03	5/29/02	Fabricating a DMOS transistor	Chuang et al
6,663,720	12/16/03	6/26/01	Method of prevent an etcher from being eroded	Wen-Peng et al
6,670,267	12/30/03	6/13/01	Formation of tungsten-based interconnect using thin ... nitride layer	Fortin
6,693,005	2/17/04	12/12/02	Trench capacitor with expanded area and method ...	King